

U.S. Department of Commerce, Patent and Trademark Office.	Atty Docket No.	Application No.
	M-11636 US	09/941,411 •
INFORMATION DISCLOSURE STATEMENT BY APPLICANT . (Use several sheets if necessary)	Applicant(s)	Confirmation No.
	DAVID POLINSKY ET AL.	6137
	Filing Date	Group
	August 28, 2001	2872

## U.S. Patent Documents

*Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
FA	A1	4,317,611	Petersen			
FA	A2	5,024,500	Stanley et al.			
FA	A3	5,629,790	Neukermans et al.			
FA	A4	5,914,801	Dhuler et al.			
FA	A5	5,969,848	Lee et al.			
FA	A6	5,974,207	Aksyuk et al.			
FA	A7	6,025,951	Swart et al.			
FA	A8	6,031,946	Bergmann et al.			
FA	A9	6,097,860	Laor			
	A10					
	A11					

## Foreign Patent Documents

Document	Date	Country	Class	Subclass	Yes	No
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## OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)

FA	C1	"Integrated Polysilicon and DRIE Bulk Silicon Micromachining for an Electrostatic Torsional Actuator," Jer-Liang Andrew Yeh et al., <i>Journal of Microelectromechanical Systems</i> , Vol. 8, No. 4, December 1999, pp. 456-465				
FA	C2	"A Flat High-Frequency Scanning Micromirror," Robert A. Conant et al., Solid-State Sensor and Actuator Workshop, Hilton Head Island, South Carolina, June 4-8, 2000, pp. 6-9				
FA	C3	"Wavelength Add-Drop Switching Using Tilting Micromirrors," Joseph E. Ford et al., <i>Journal of Lightwave Technology</i> , Vol. 17, No. 5, May 1999, pp. 904-910				
	<del>C4</del>	<del>"MEMS Variable Optical Attenuator For DWDM Optical Amplifiers," Bo Moller Andersen et al., Lucent Technologies, 2 pages</del> No date				
	<del>C5</del>	<del>Dialog Search dated June 19, 2001</del> Every reference needs to be listed with all pertinent information.				
	<del>C6</del>	<del>Dialog Search dated June 19, 2001</del> Every reference needs to be listed with all pertinent information.				

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Date Considered

8/18/03

\*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.